



FIG 1A

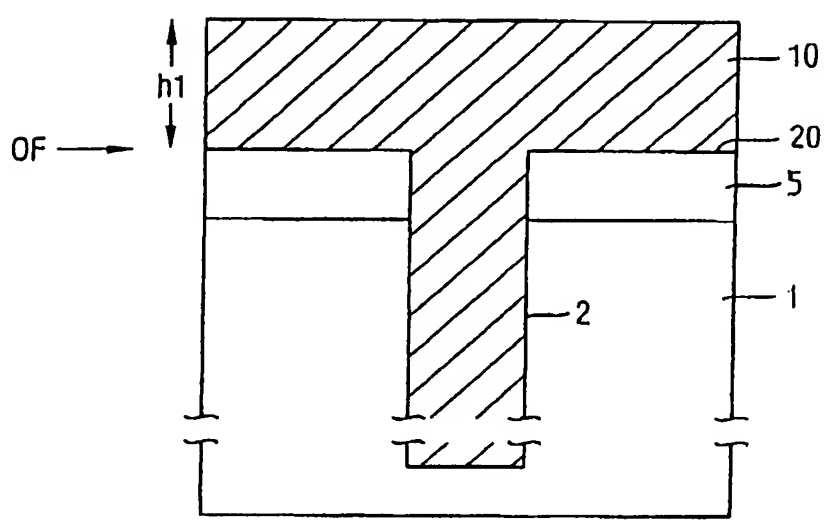
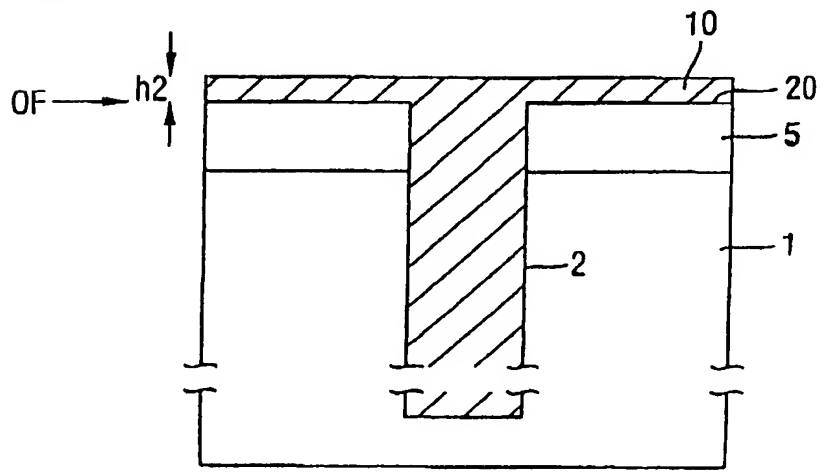


FIG 1B



REPLACEMENT SHEET

Title: FABRICATION METHOD FOR A
SEMICONDUCTOR STRUCTURE
HAVING A PARTLY FILLED TRENCH

Applicant: Hansel et al.

Serial No. 10/660,091 **Ref No.:** 1406/166

FIG 1C

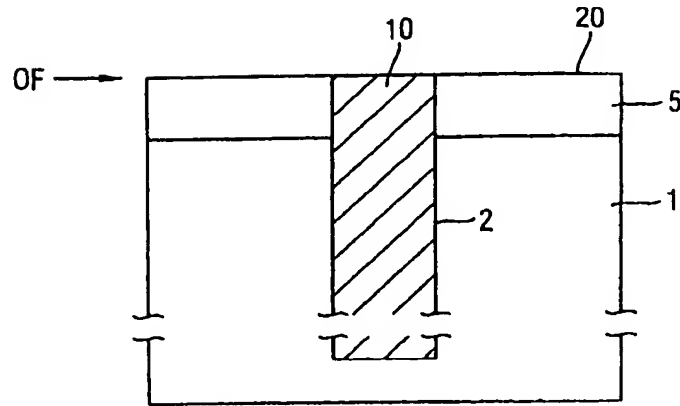
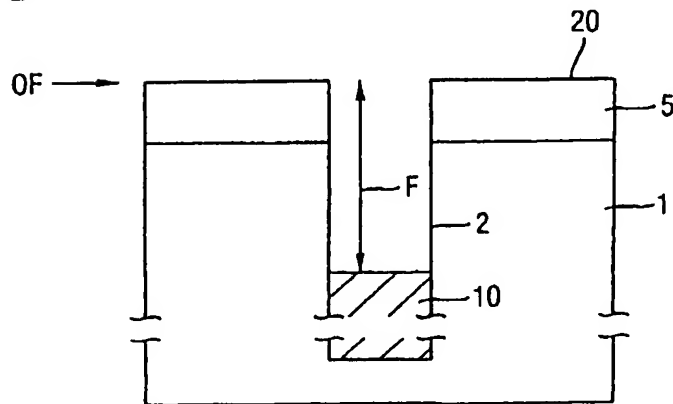


FIG 1D



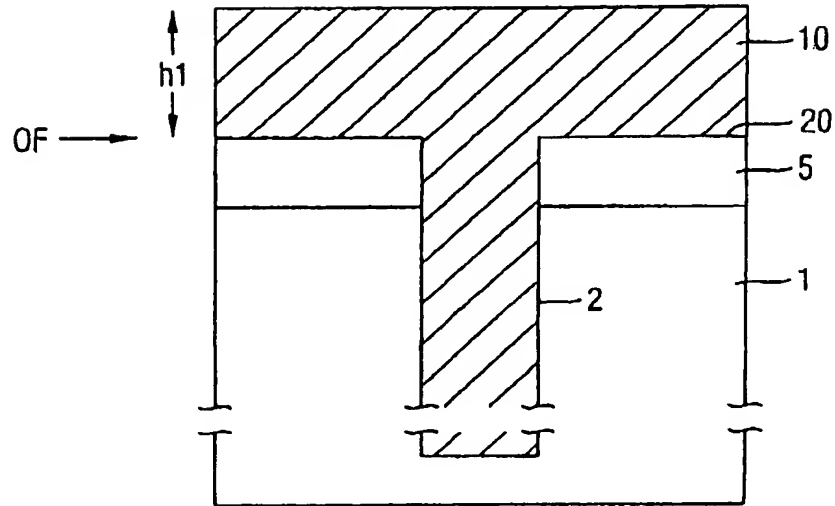
REPLACEMENT SHEET

Title: FABRICATION METHOD FOR A
SEMICONDUCTOR STRUCTURE
HAVING A PARTLY FILLED TRENCH

Applicant: Hansel et al.

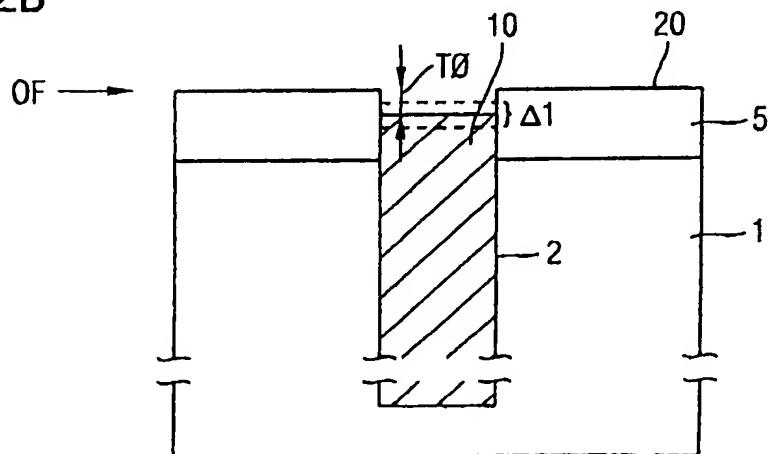
Serial No. 10/660,091 Ref No.: 1406/166

FIG 2A



(PRIOR ART)

FIG 2B



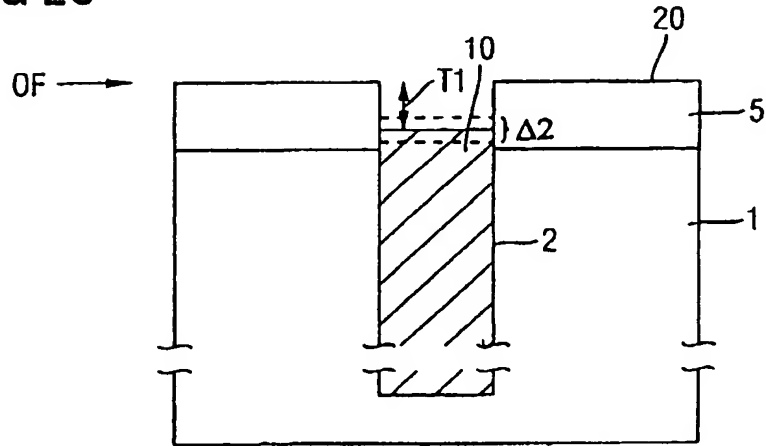
(PRIOR ART)

Title: FABRICATION METHOD FOR A SEMICONDUCTOR STRUCTURE HAVING A PARTLY FILLED TRENCH

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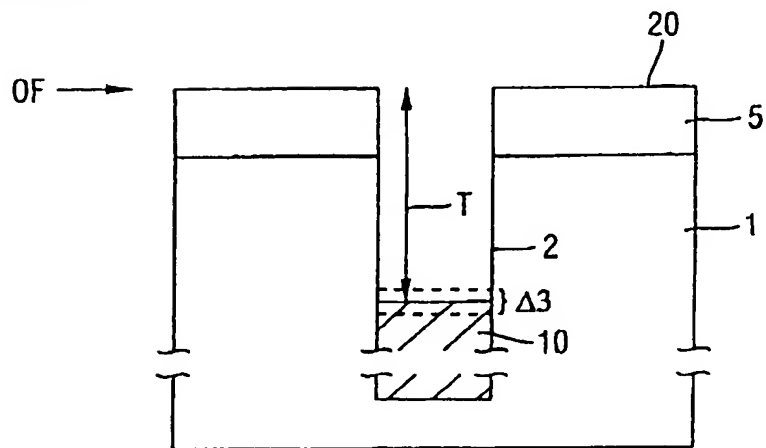
Serial No. 10/660,091 Ref No.: 1406/166

FIG 2C



(PRIOR ART)

FIG 2D



(PRIOR ART)